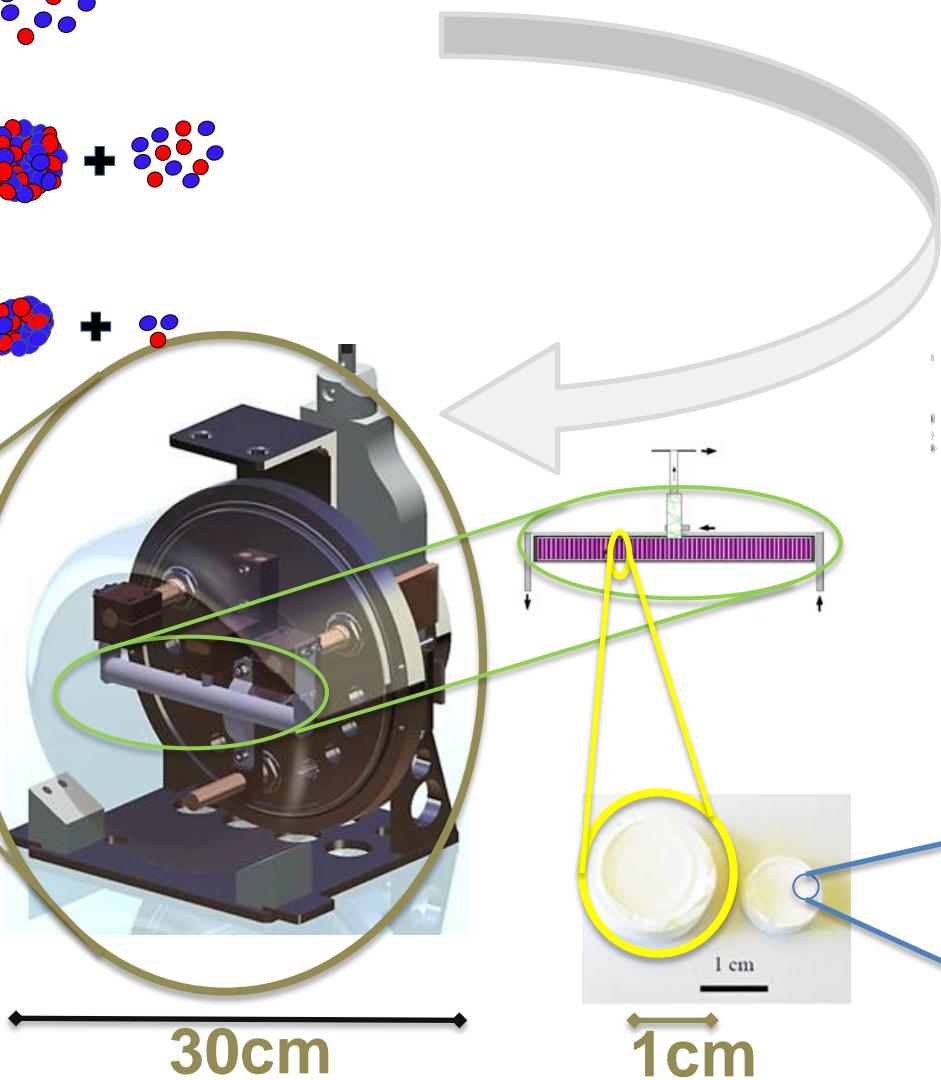
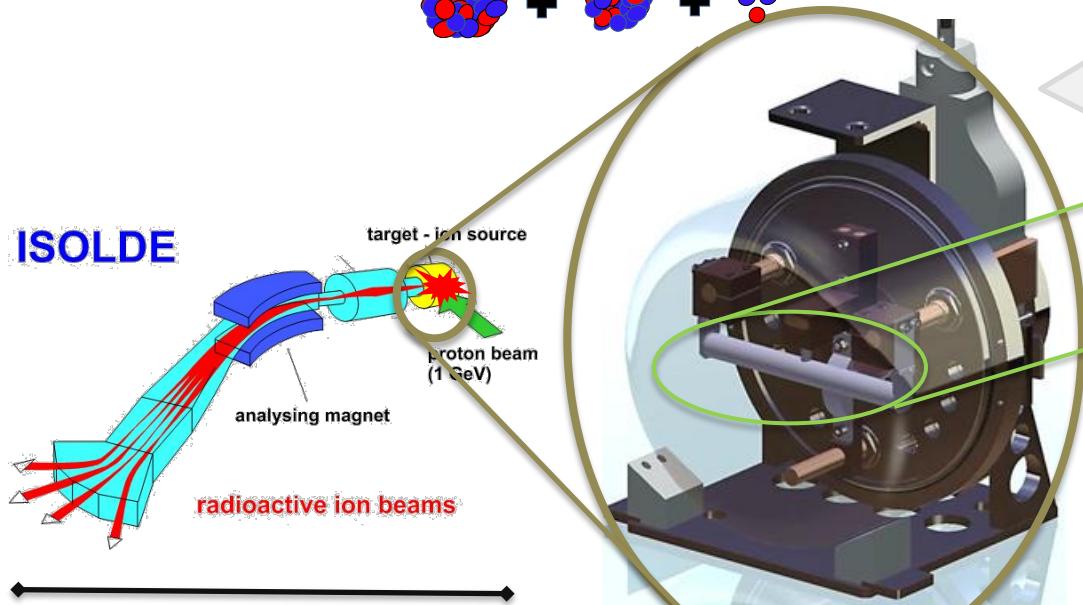
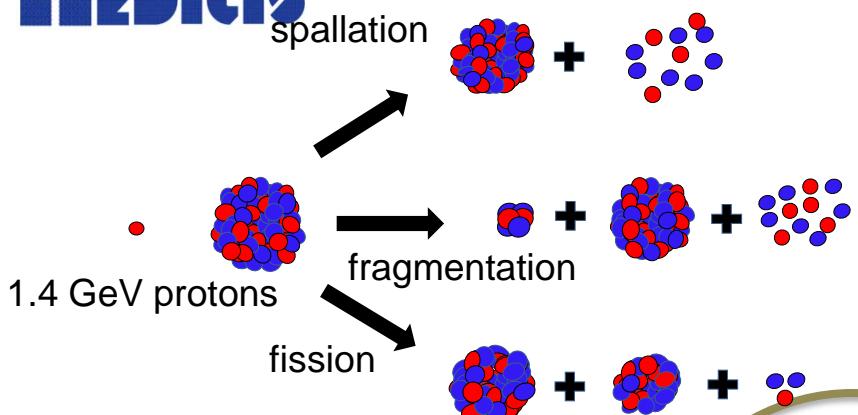
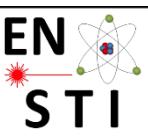
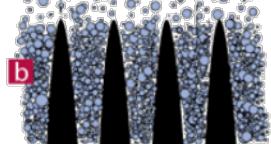


# Nanomaterials for Refractory spallation targets (isotopes) and for Microfabrication

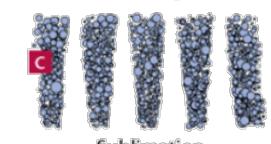
# Radiosotope beams by ISOL method



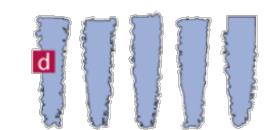
growing ice crystals concentrated colloids



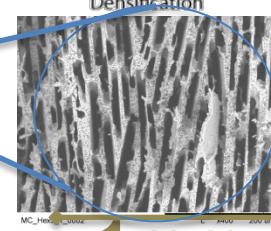
Freezing



Sublimation



Densification



1mm

# For what type of physics?



## Nuclear physics

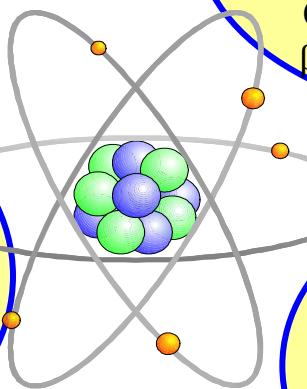
Nuclear Decay Spectroscopy and Reactions  
Structure of Nuclei  
Exotic Decay Modes

## Fundamental physics

Direct Mass Measurements,  
Dedicated Decay Studies - WI  
CKM unitarity tests, search for  
 $\beta-\nu$  correlations, right-handed  
currents

## Atomic physics

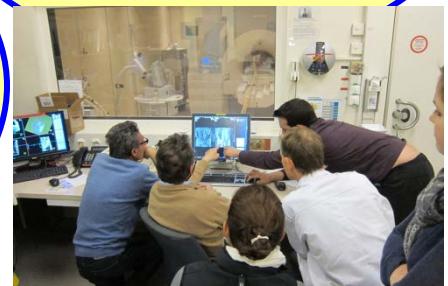
Laser Spectroscopy and direct Mass Measurements  
Radii, Moments, Nuclear Binding Energies



$$f(N, Z)$$

## Applied physics

Condensed matter physics and Life sciences  
Tailored Isotopes for Diagnosis and Therapy  
**MEDICIS Project**



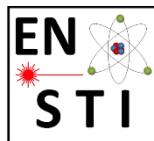
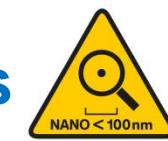
**Ion. Pot. (At) = 9.31751(8) eV**  
Nature Comm. 14 May 2013



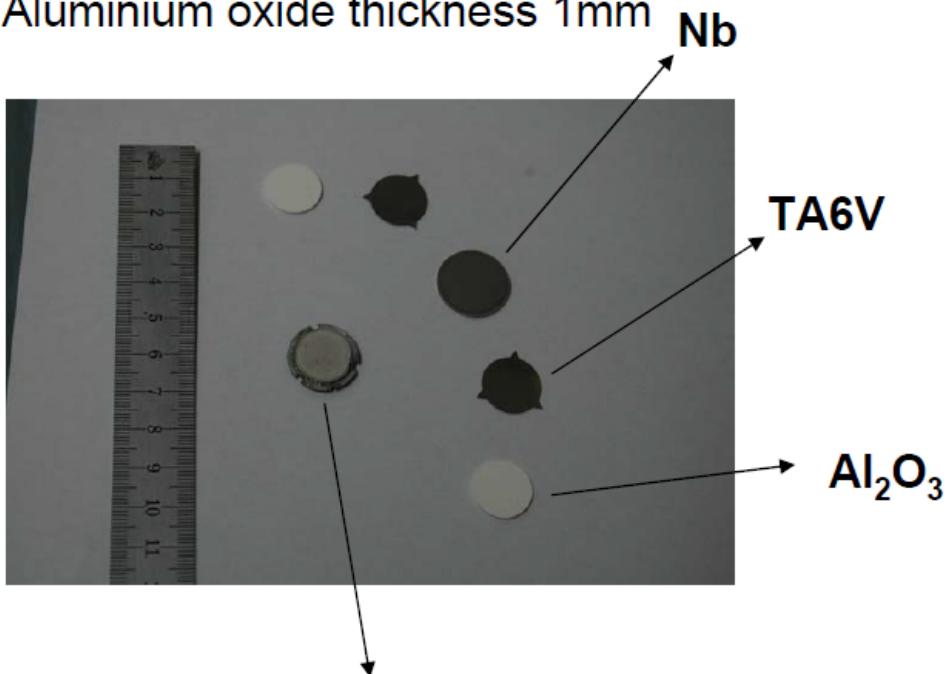
## Astrophysics

Dedicated Nuclear Decay/Reaction Studies  
Element Synthesis, Solar Processes

# Refractory metal/oxide ceramics composites at very high temperature



- Niobium metal foil thickness 0.5mm
- Ti90 / Al6 / V4 (TA6V) alloy foil thickness 0.1mm
- Aluminium oxide thickness 1mm



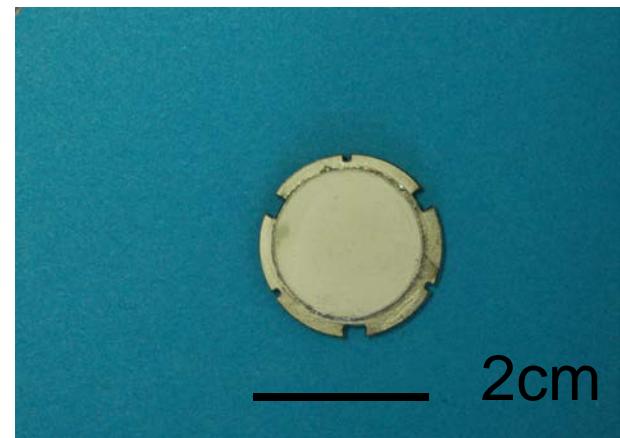
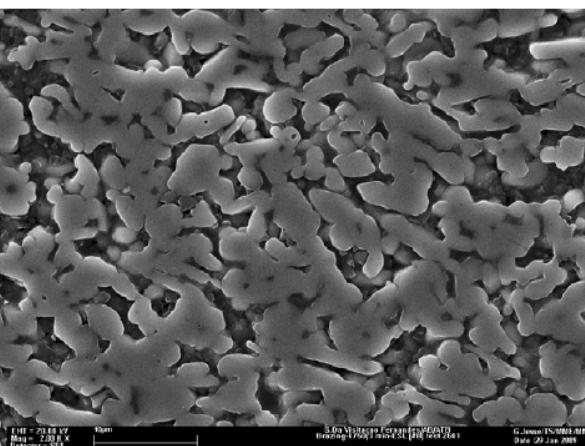
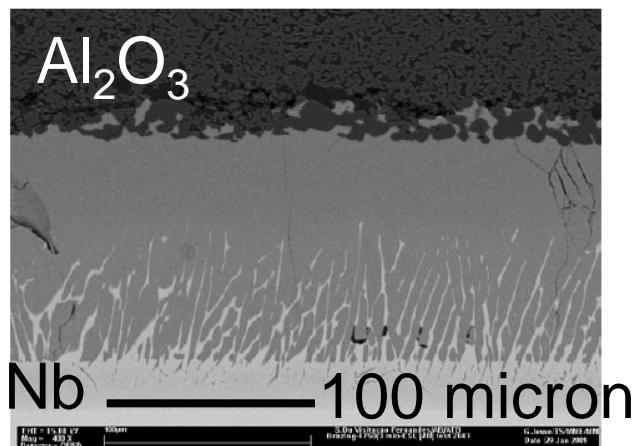
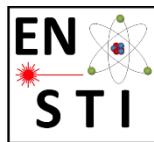
**Nd: YAG** laser  
(0.01mm, 1J, 35 W,  
610mm/min)



# Reactive metal/oxide brazing

## Stable at high T

### to increase heat dissipation from oxides



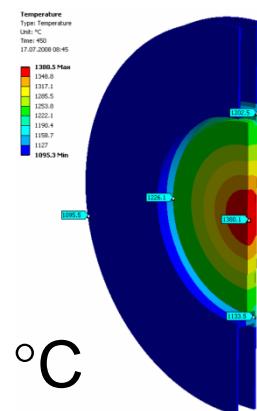
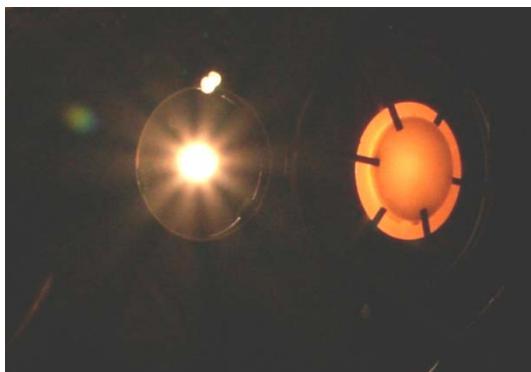
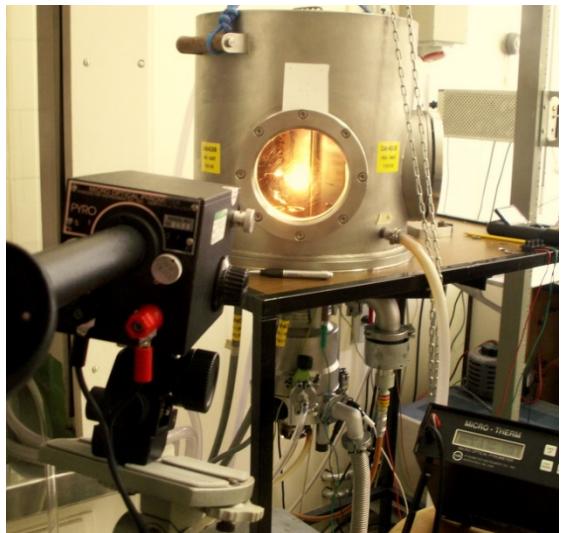
Brazing interface Al<sub>2</sub>O<sub>3</sub>/ TA6V/ Nb

Al<sub>2</sub>O<sub>3</sub> microstructure after brazing

Material	Density (g/cm <sup>3</sup> )	Melting point (°C)	Thermal conductivity (W/(m·K))
Al <sub>2</sub> O <sub>3</sub>	2.75 (%69.5 TD)	2054	3.0 - 3.7 (T = 1400°C)
TA6V	4.42	1650	-
Nb	8.57	2468	50-80 (T = 1273 - 2073°C)

## 2 relevant properties (for us, maybe also for you ?)

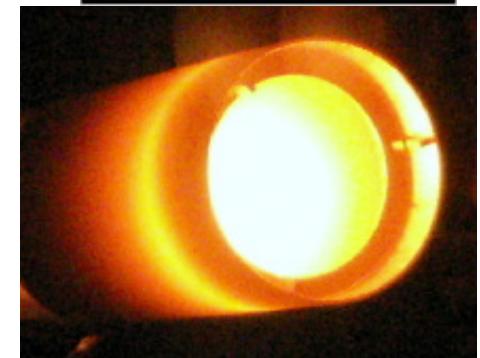
Thermal conductivity & contact conductance



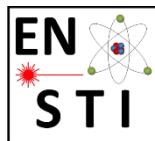
$$K > 20'000 \text{ W/m}^2 \text{ K}$$

Resist dilatation/stress at  $T=1400 \text{ }^\circ\text{C}$   
and  $\Delta T = 400 \text{ }^\circ\text{C}$

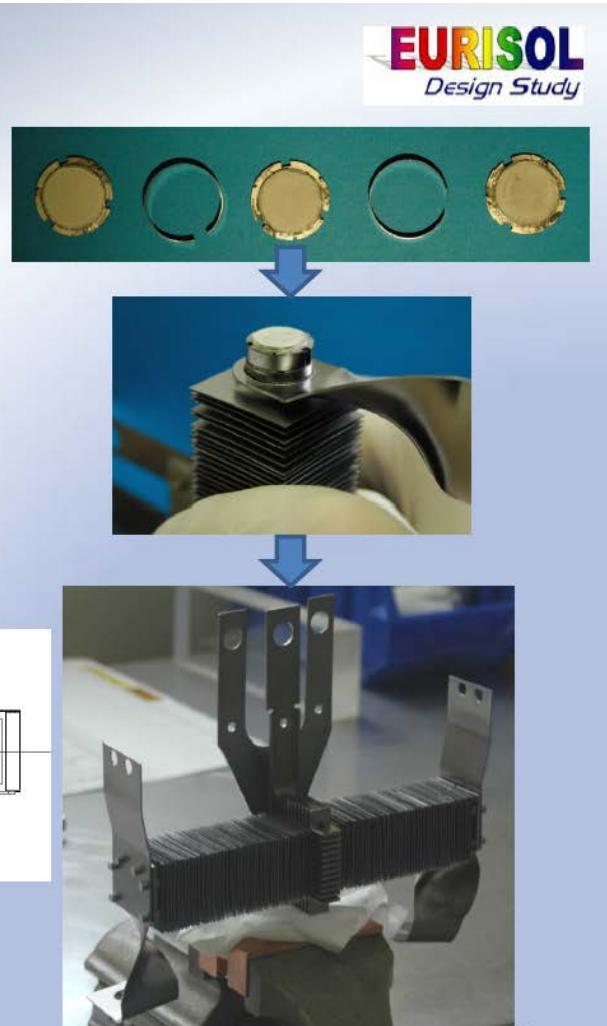
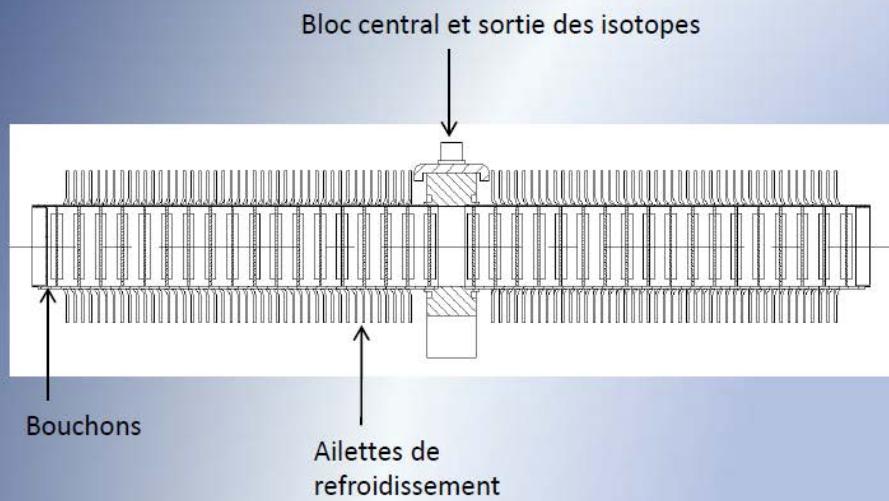
Defective brazing



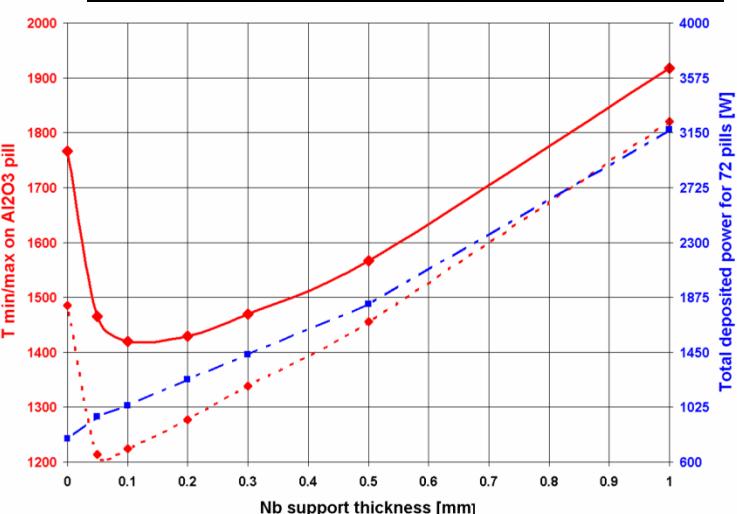
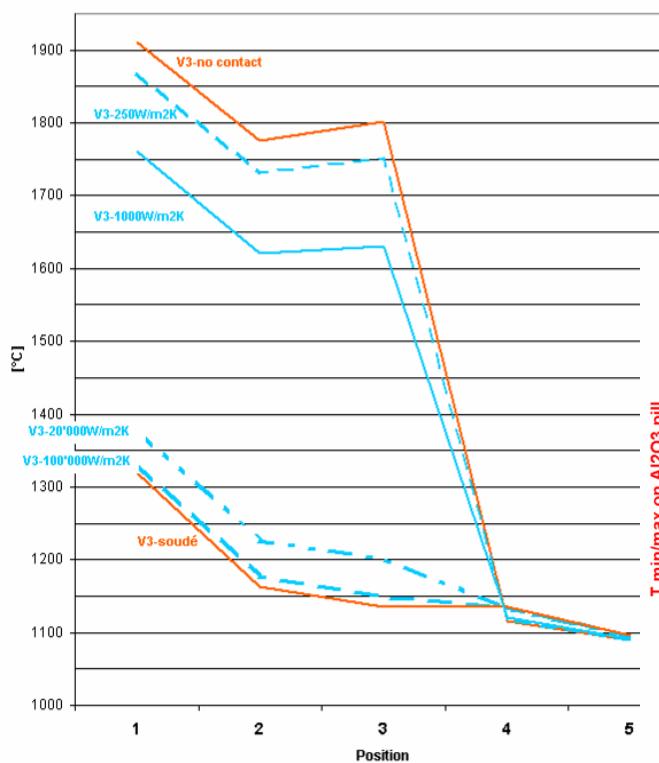
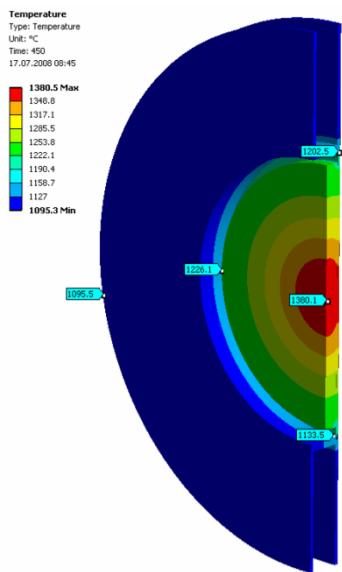
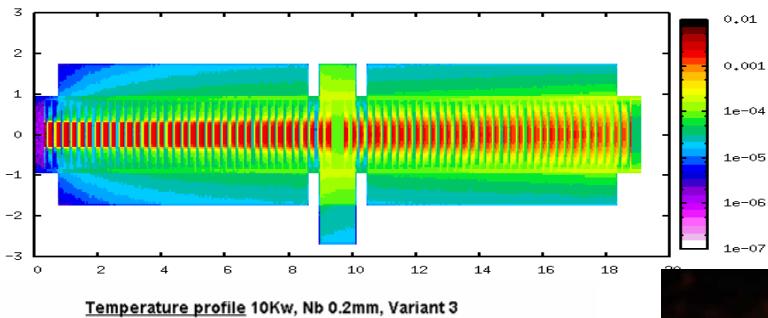
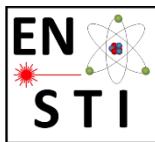
# Loading a full cylinder



Montage des 36 doubles pilules :



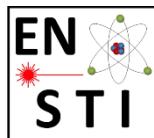
# Thermal conductivity & contact conductance



Otherwise, the ceramics does not stand the beam/heat

T. Stora

# Test under beam irradiation : Highest proton beam intensity ever on oxide target



4004 Wesbrook Mall  
Vancouver, BC,  
Canada V6T 2A3

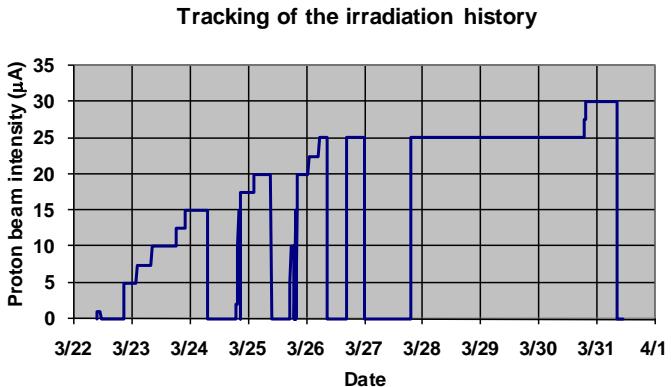
Meeting Note

## EURISOL high power oxide target test

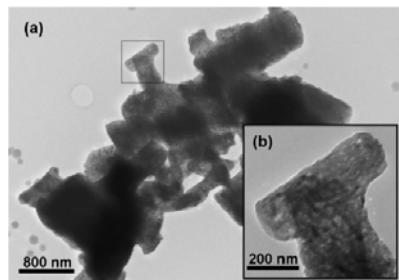
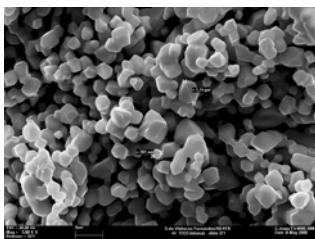
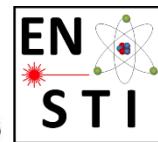
Vancouver, CA

Note prepared by: Pierre Bricault

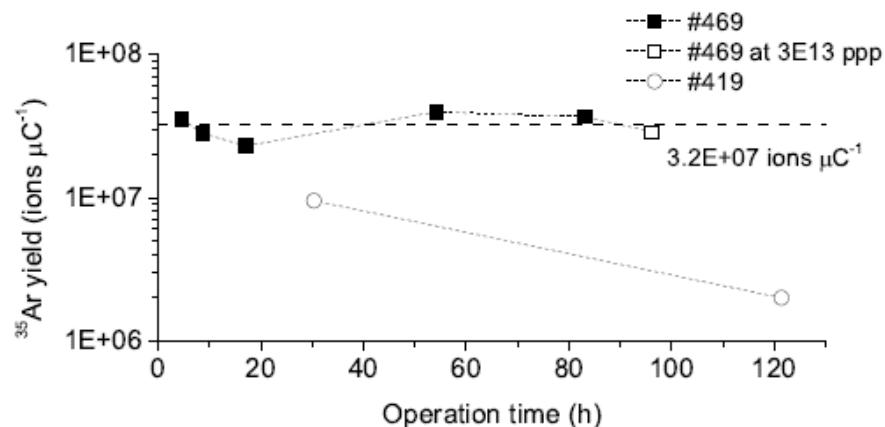
Present: Thierry Stora (CERN-ISOLDE/EURISOL), Paul Schmor, Friedhelm Ames, Pierre Bricault, Marik Domsky, Jens Lassen, Victoire Hannemayer, Chad Fisher



# Porous refractory nano-ceramics for other applications ?



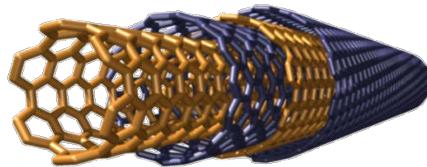
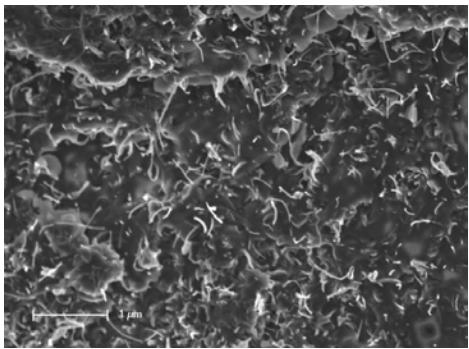
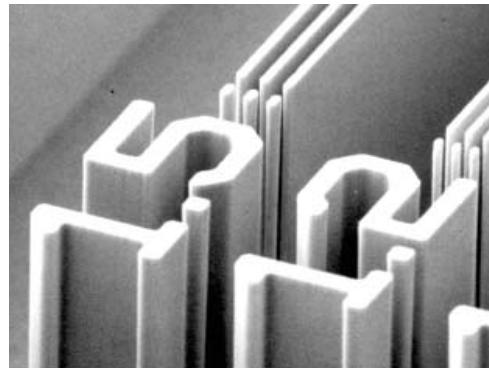
$\text{Y}_2\text{O}_3$ ,  $\text{CaO}$ ,  
 $\text{Al}_2\text{O}_3$  with unidirectional porosity,  
 $\text{BeO}^*$ ,  $\text{ZrO}_2^*$   
 $\alpha\text{-SiC}$ ,  $\alpha\text{-SiC}/\text{Carbon nanotubes}$ ,  
 $\text{TiC}$  (ongoing)  
 $\text{UC}_2/\text{Carbon nanotubes}$  (ongoing)  
\*: Tested under beam at high T



Highly porous microstructure stable under beam irradiation  
at high T.

T. Stora

# Nanocomposites for microfabrication

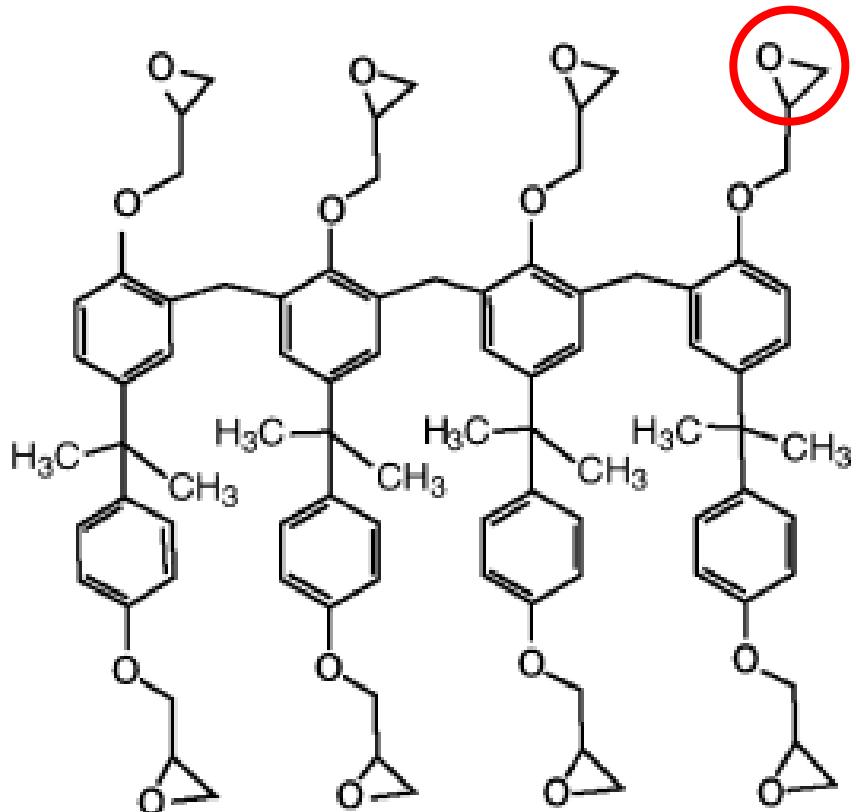


PhD thesis of M. Mionic @EPFL

# Matrix for our composites: SU8

## Polymer

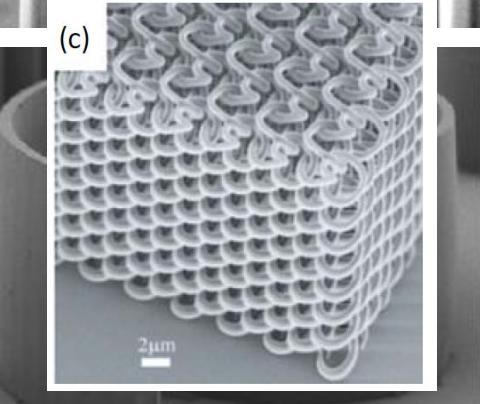
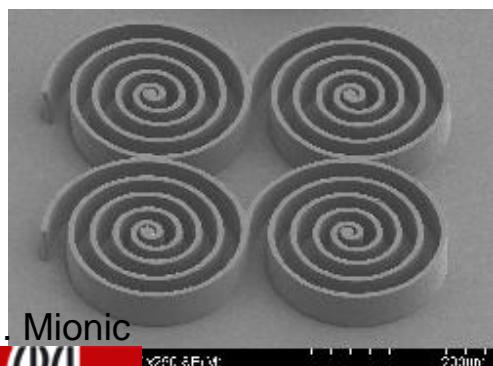
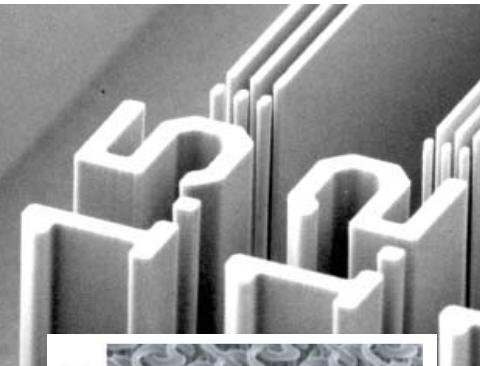
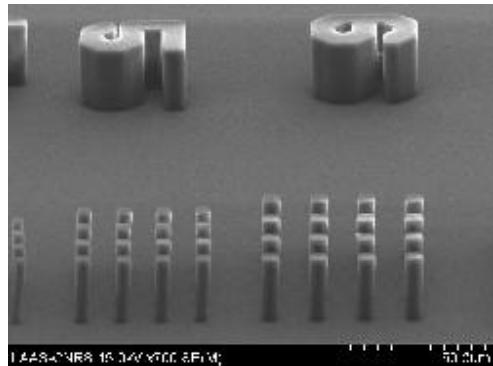
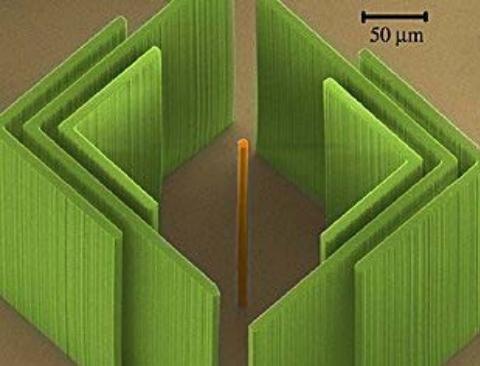
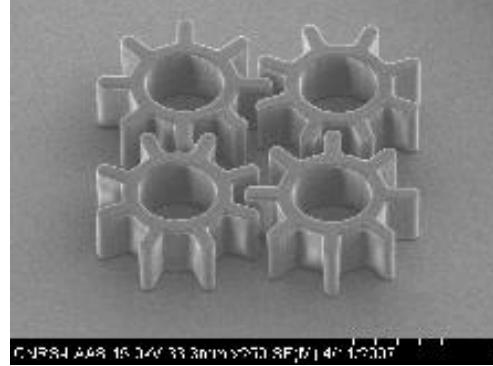
UV curable negative ton **epoxy resin**



## Applications

- MEMS (Micro-electro-mechanical systems)
- MOMES Optoelectronic
- BioMEMS Lab-On-a Chip
- Advanced packaging
- Nanoimprint
- Coating layer
- Bonding layer
- Microfluidic
- LIGA-Micro mould
- Micro-machining
- Stamp manufacturing
- Inkjet manufacturing
- 3D interconnect

# Illustration for applications of SU8



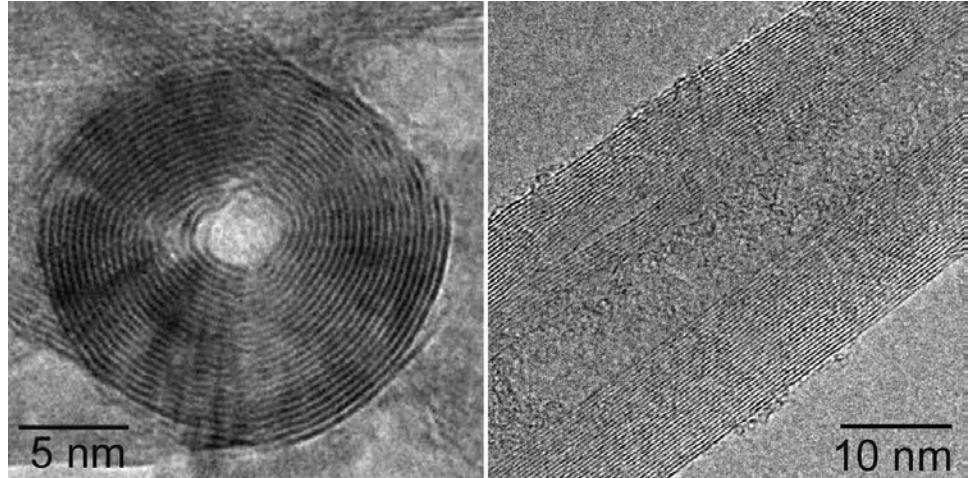
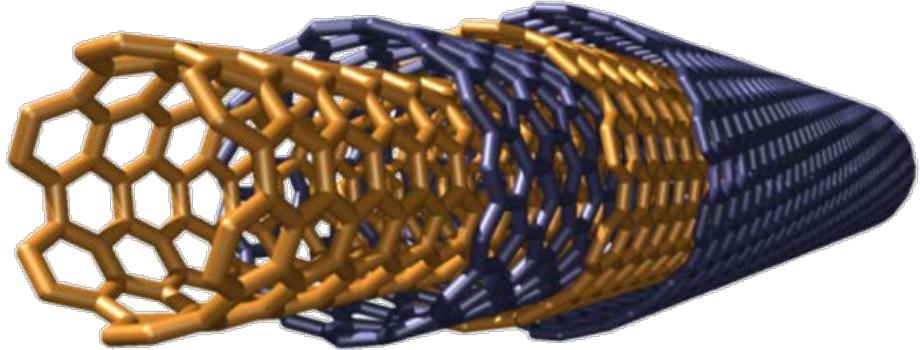
## Advantages:

- Processable with UV
- high aspect ratio structures

## Disadvantages:

- Electrical insulator
- Thermal insulator
- Brittle

# CNTs



Diameter (from  $\square 4\text{\AA}$  to  $\square 100\text{nm}$ )

Length (from  $200\text{nm}$  to  $\square 20\text{cm}$ )

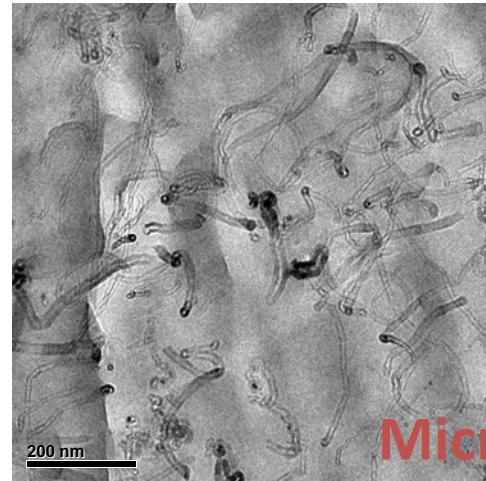
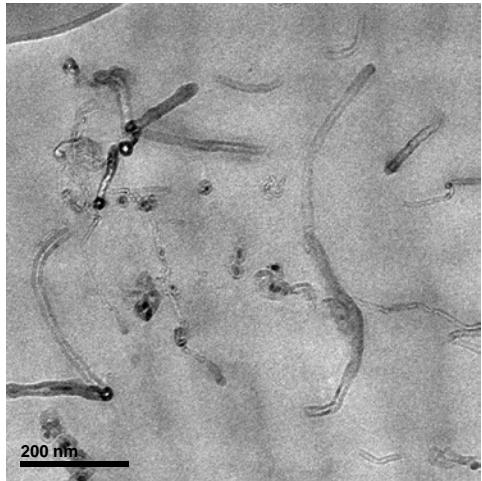
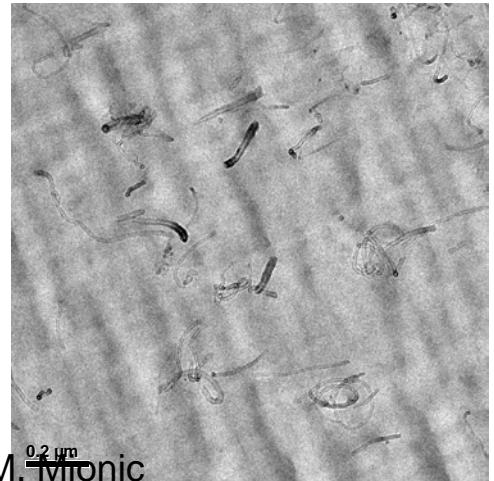
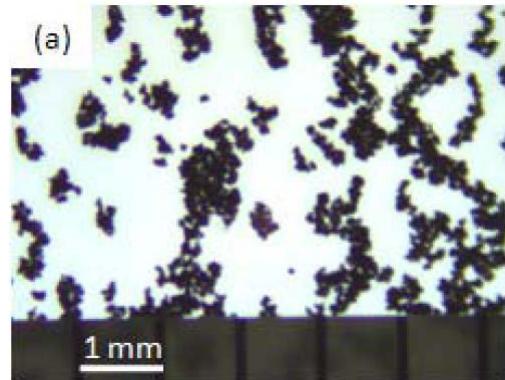
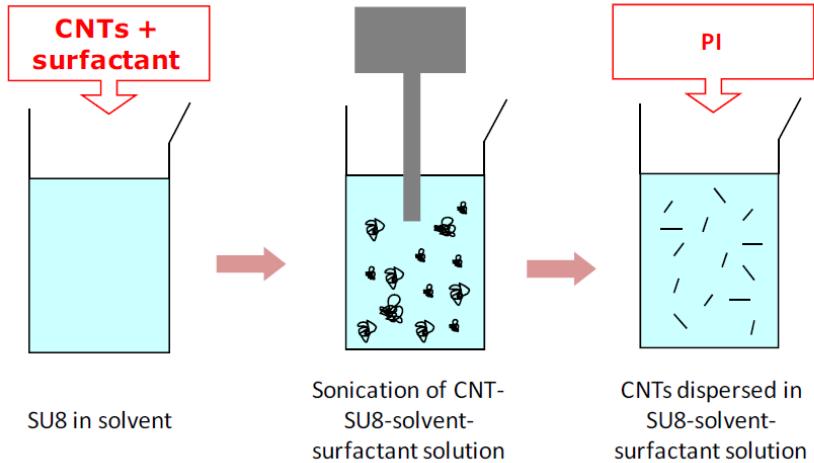
High mechanical strength ( $E_y \square 1\text{TPa}$ )

High thermal conductivity ( $\square 3000\text{W/mK}$ )

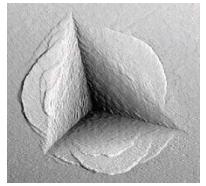
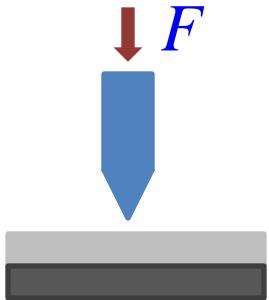
Low resistivity ( $> 10^{-8} \square\text{m}$ )

Low density (from  $1.3$  to  $2.6\text{g/cm}^3$ )

# Control of aggregation/network with surfactant and solvent

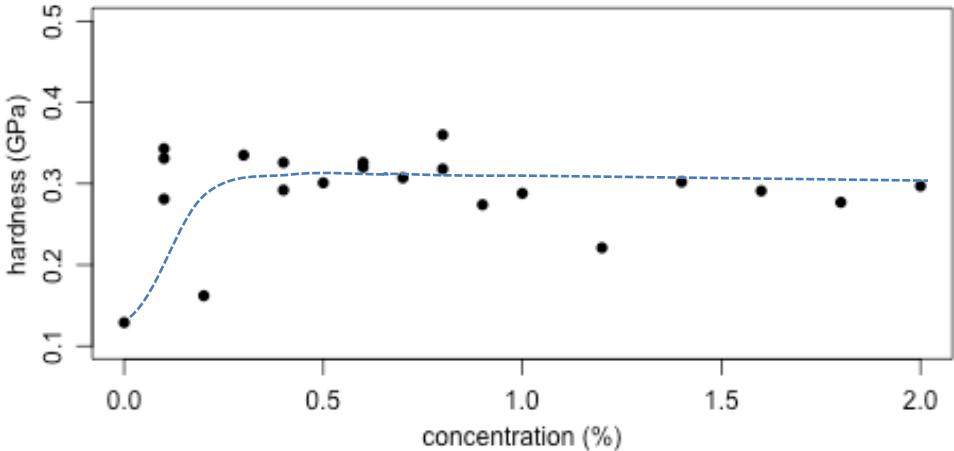


# Mechanical test: nanoindentation



$$H = \frac{F_{\max}}{A}$$

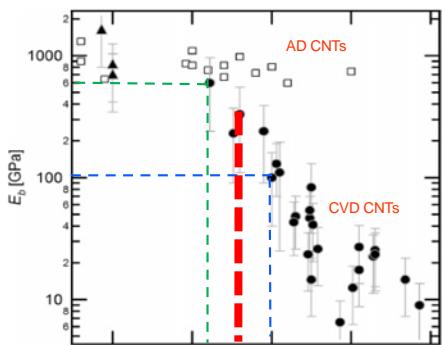
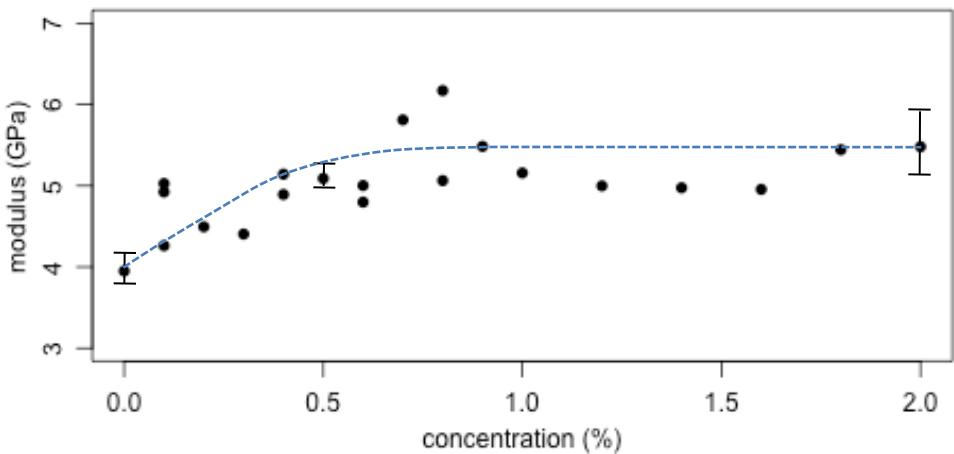
$$E = \frac{S(1-\nu^2)\sqrt{\pi}}{2\beta\sqrt{A}} - \frac{S\sqrt{\pi}(1-\nu_i^2)}{E_i}$$



$E = E_{\text{CNT}} V_{\text{CNT}} + E_{\text{SU8}} (1 - V_{\text{CNT}})$   
 (role of mixture)

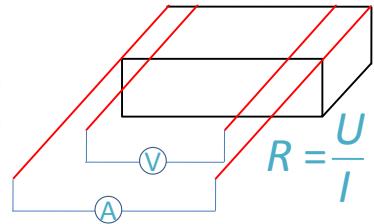
$d_{\text{aver.}} \approx 13 \text{ nm}$

$E_{\text{CNT}} \approx 300 \text{ GPa}$

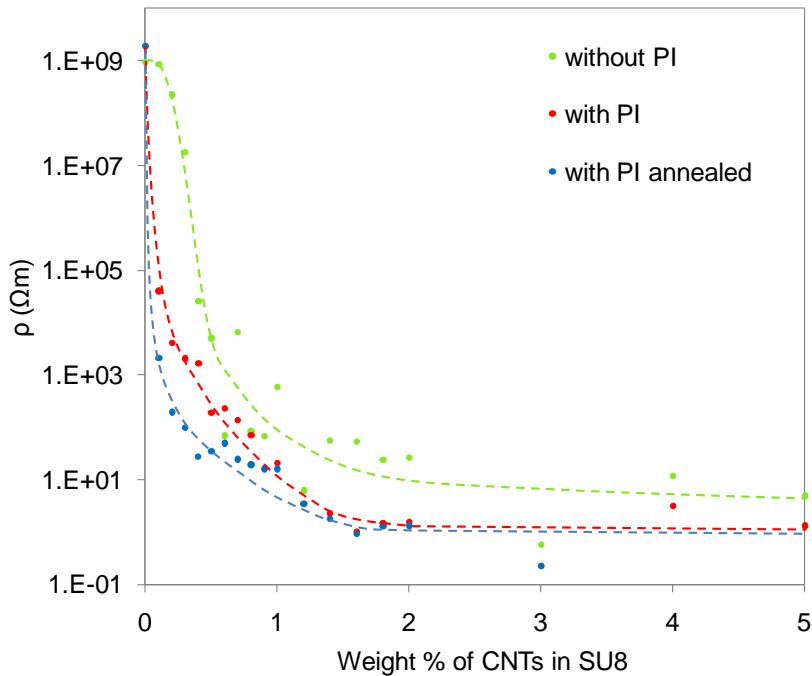


CNTs	E <sub>Theory</sub>	E <sub>Measured</sub>
0.2%	4.5GPa	4.5GPa
0.8%	6.3GPa	6.2GPa

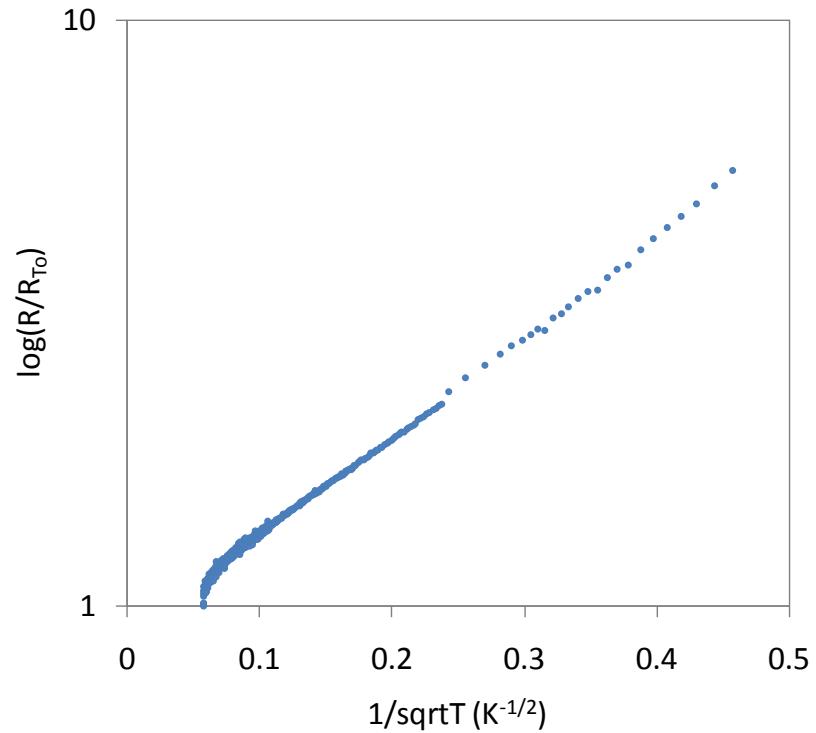
# Resistivity measurement



Percolation threshold



Conduction mechanism



< 0.2wt% of CNTs => homogeneous arrangement of CNTs

$$R \propto T^{-\alpha} \quad \alpha = \frac{1}{2}$$

In generally attributed to the presence of Coulomb gap

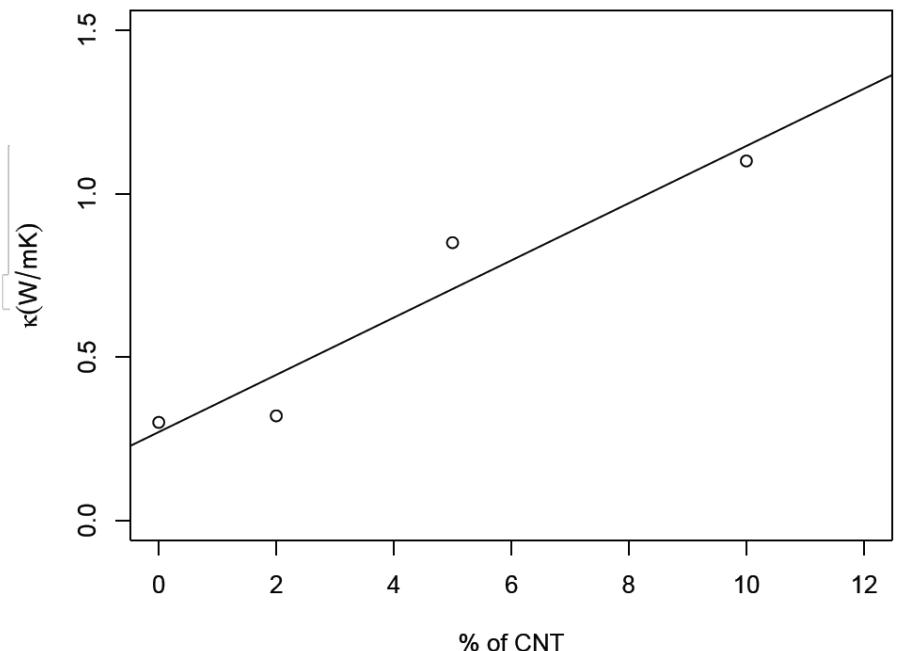
- In the homogeneous system of localized interacting e
- in the form of charging E in a granular metal systems

Efros and Shklovskii, JPC 1975,

P. Sheng, PRL 1973

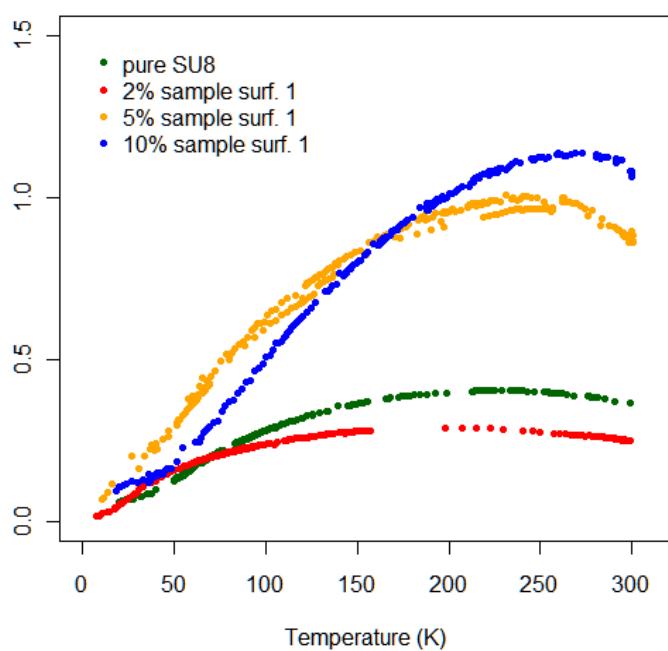
# Thermal conductivity

Thermal conductivity  
at room temperature

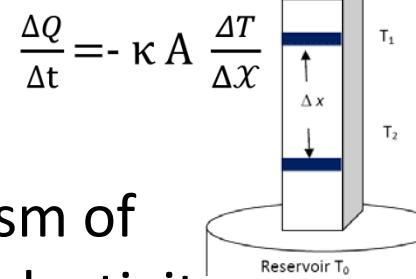


With 10wt% of CNTs – 4 fold increase

Mechanism of  
thermal conductivity



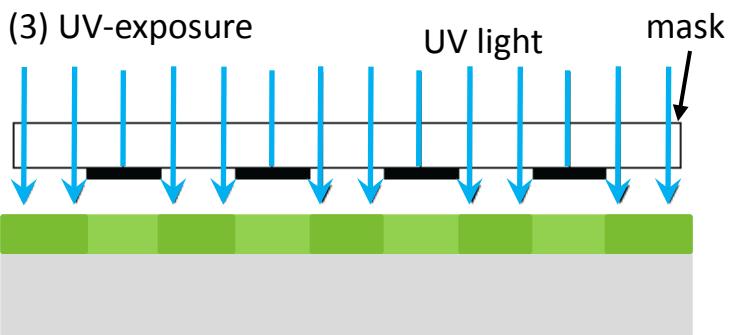
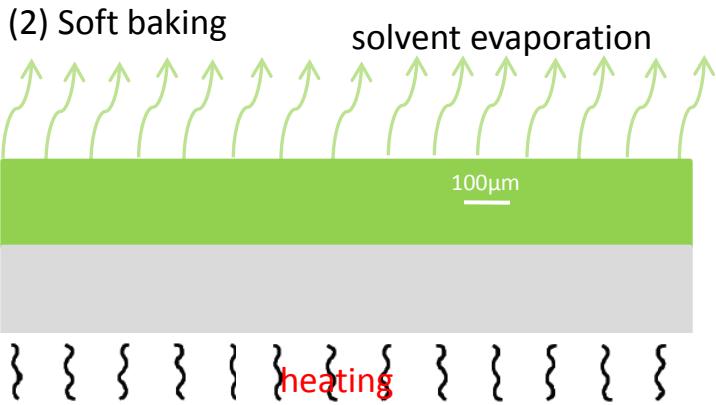
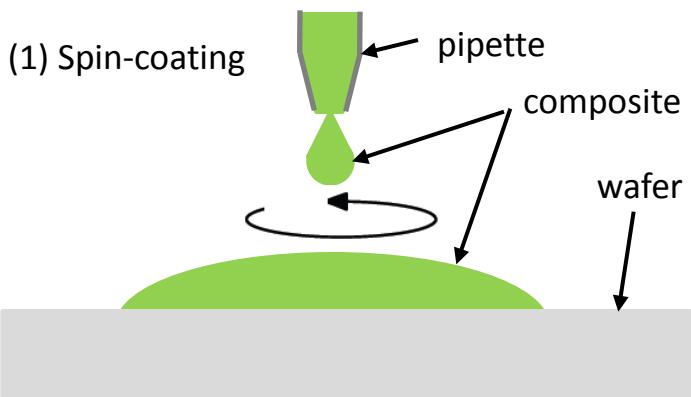
Governed by lattice thermal conductance



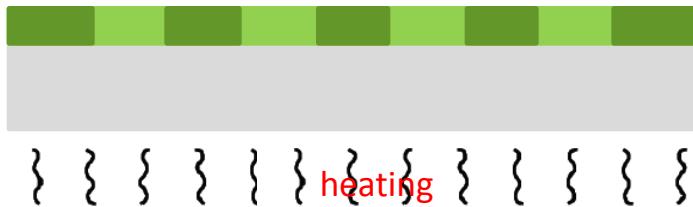
# Processing of CNTs-SU8 composite

- Photolithography
- Inkjet printing
- Screen printing

# Photolithography



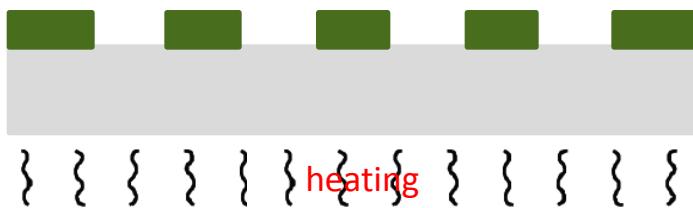
(4) Post-exposure bake



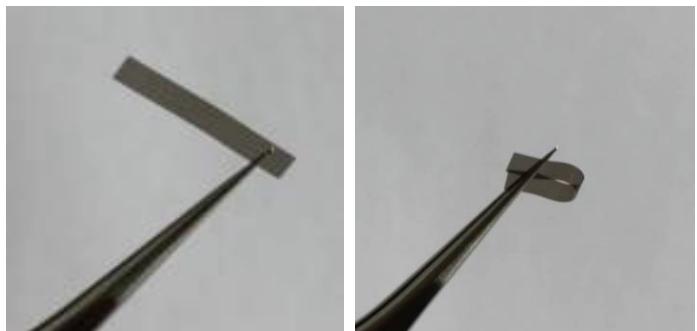
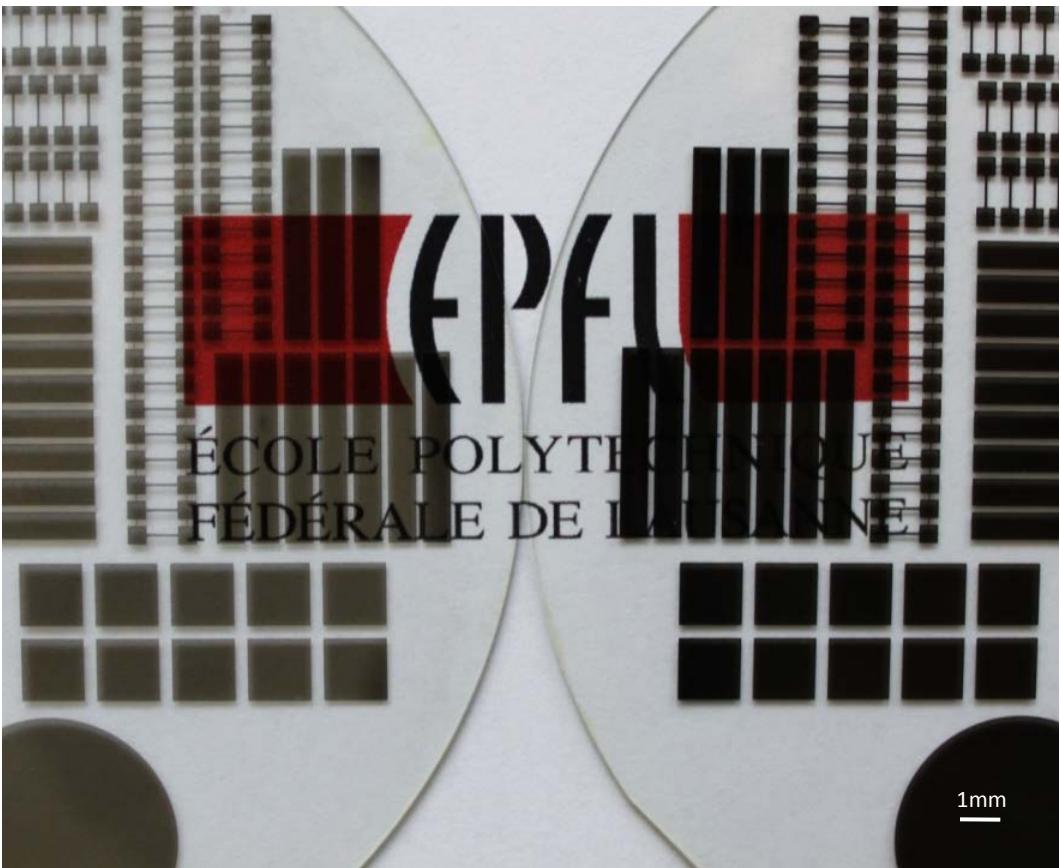
(5) Development



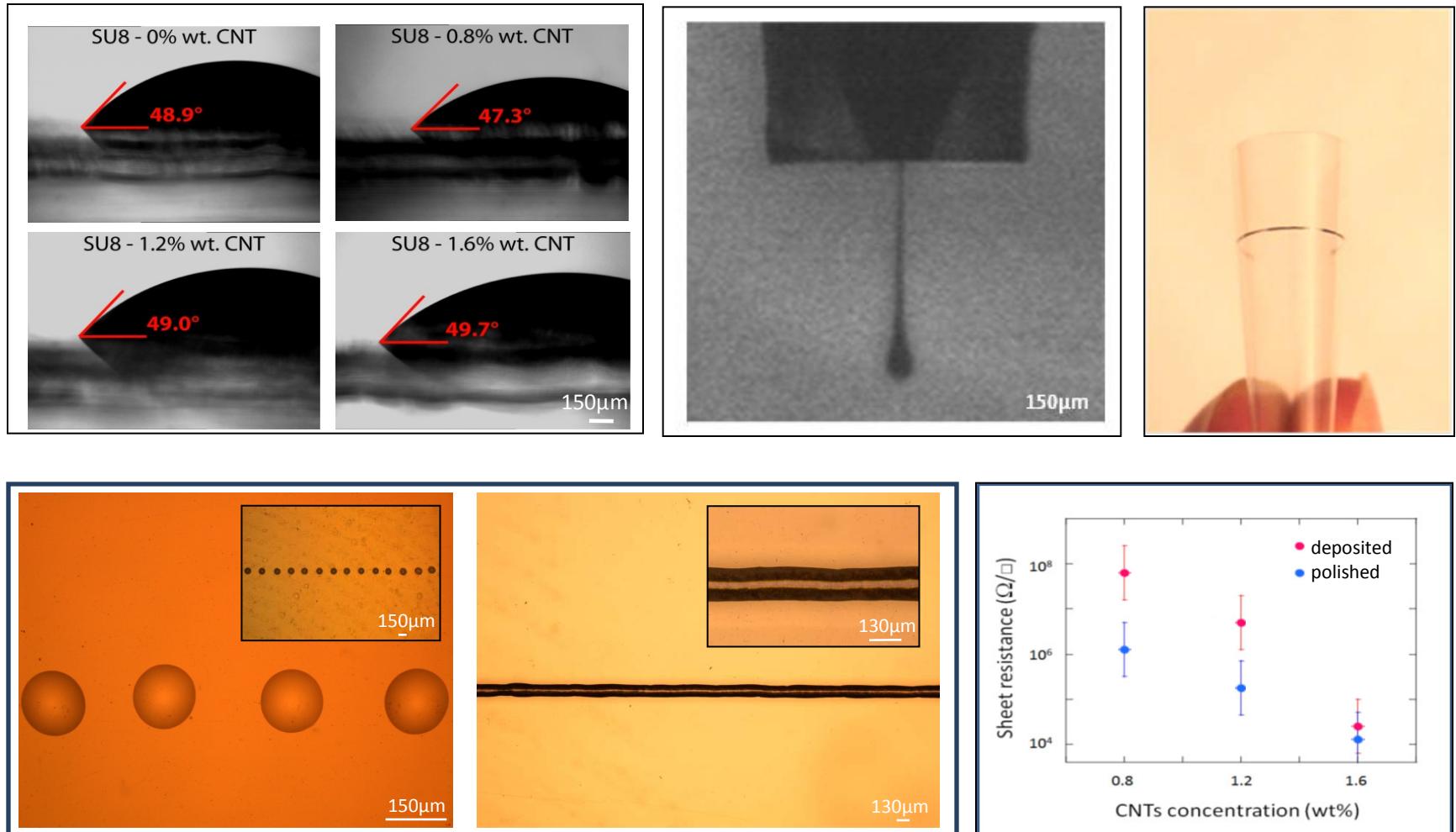
(6) Hard bake



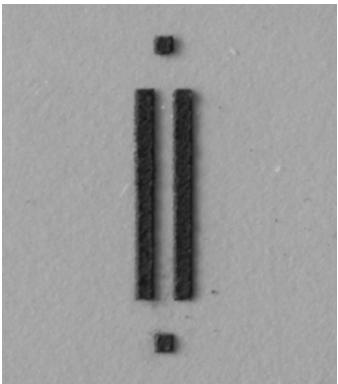
# Photolithography



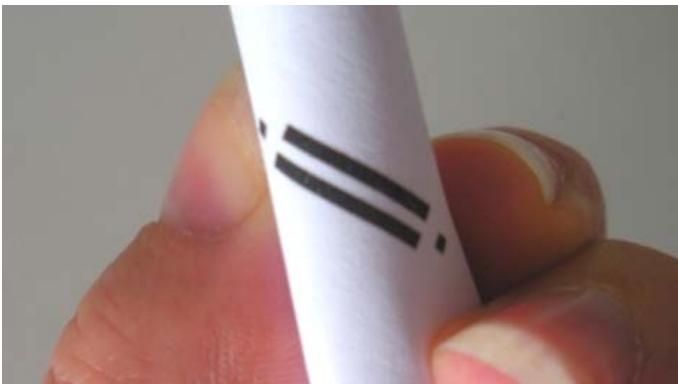
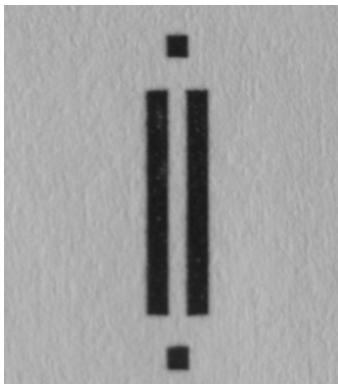
# Inkjet printing



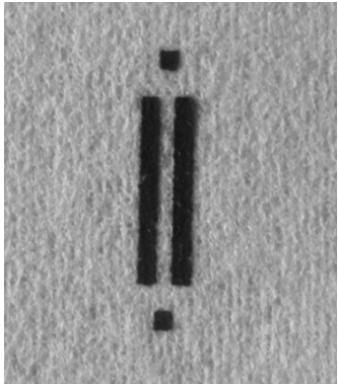
# Screen printing



On plastic foil



On paper

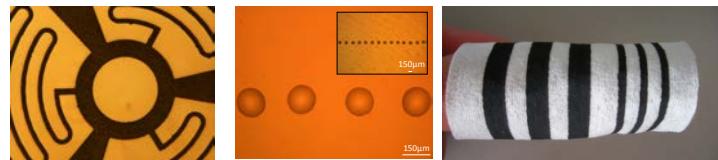
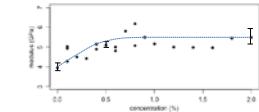
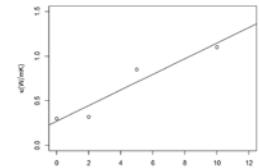
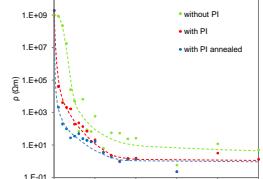
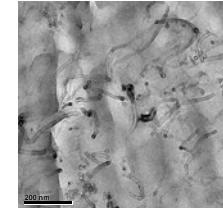


On textile

# Summary and outlook

## Summary

- Preparation of homogeneous CNTs-SU8 composites
- Turned into good electrical conductor
- Improved thermal conductivity
- Better mechanical response
- Easy processability

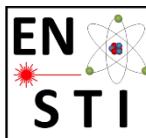


## Outlook

- Composite ready for real applications

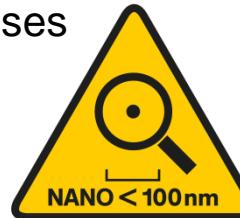


## Outlook, references



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the TISD team, ISOLDE, EN-MME, TE-VSC at CERN

(some)  
partners:



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